

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	1404	"250"/\$.ccls. and electron adj beam and optical adj system	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 12:55
S2	142	("250"/\$.ccls. and electron adj beam and optical adj system) and lens and shield	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/23 07:57
S3	9	(("250"/\$.ccls. and electron adj beam and optical adj system) and lens and shield) and auger	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/12 09:58
S4	3369	250/310-311.ccls.	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 07:38
S5	120	250/310-311.ccls. and electron adj beam and lens and shield	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/12 10:34
S6	107	(250/310-311.ccls. and electron adj beam and lens and shield) and microscope	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 07:38
S7	27	secondary adj electron and backscatter and detector and SEM	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/12 12:42
S8	404	250/310-311.ccls. and SEM	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/12 12:57
S9	289	(250/310-311.ccls. and SEM) and secondary adj electron	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 09:50
S10	9	("4789787" "4894549" "5182453" "5422486" "5436460" "5444243" "5510617" "6246058" "6259094").PN.	USPAT	OR	ON	2002/12/12 14:51
S11	10	(250/310-311.ccls. and electron adj beam and lens and shield) and microscope and capacitor	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 07:38
S12	20	(250/310-311.ccls. and SEM) and secondary adj electron and magnetic adj pole	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 12:31
S13	5	(250/310-311.ccls. and SEM) and auger and deflection adj plate	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 12:34
S14	0	(250/310-311.ccls. and SEM) and virtual adj auger	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 12:32
S15	39	(250/310-311.ccls. and SEM) and auger	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 13:27

S16	3	("4126781").PN.	USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2002/12/13 13:27
S17	0	"250"/\$.ccls. and electron adj beam and optical adj system and dual adj pole adj magnetic adj lens	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 14:21
S18	70	"250"/\$.ccls. and electron adj beam and optical adj system and magnetic adj pole	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 15:42
S19	4	"250"/\$.ccls. and electron adj beam and optical adj system and spherical adj capacitor	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 14:56
S20	1	"250"/\$.ccls. and electron adj beam and optical adj system and electrostatic adj capacitor	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 14:57
S21	2	"250"/\$.ccls. and electron adj beam and optical adj system and electrostatic adj detector	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 14:57
S22	0	"250"/\$.ccls. and electron adj beam and optical adj system and duel adj magnetic adj pole	USPAT; EPO; JPO; DERWENT	OR	ON	2002/12/13 15:43
S23	6	(("4806754") or ("5770863")).PN.	USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2002/12/13 16:13
S24	21	scanning adj electron adj microscope and secondary adj electron and lens and shield and capacitor	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 15:38
S25	48	scanning adj electron adj microscope and auger adj electron and deflect\$4 and analyz\$5	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 14:24
S26	39	(scanning adj electron adj microscope and auger adj electron and deflect\$4 and analyz\$5) and "250"/\$.ccls.	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 13:25
S27	10	((scanning adj electron adj microscope and auger adj electron and deflect\$4 and analyz\$5) and "250"/\$.ccls.) and shield	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 13:27
S28	0	((scanning adj electron adj microscope and auger adj electron and deflect\$4 and analyz\$5) and "250"/\$.ccls.) and shield) and gradient	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 13:27
S29	13	scanning adj electron adj microscope and deflect\$4 and analyz\$5 and shield and gradient	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 13:28

S30	108	scanning adj electron adj microscope and secondary adj electron and lens and shield	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 14:11
S31	18	(scanning adj electron adj microscope and secondary adj electron and lens and shield) and auger	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 14:12
S32	10	scanning adj electron adj microscope and auger adj electron and deflect\$4 and capacitor	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 16:38
S33	680	scanning adj electron adj microscope and secondary adj electron and resolution	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 15:52
S34	437	(scanning adj electron adj microscope and secondary adj electron and resolution) and "250"/\$.ccls.	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 15:39
S35	343	scanning adj electron adj microscope and secondary adj electron and resolution same beam and "250"/\$.ccls.	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 15:53
S36	247	scanning adj electron adj microscope and secondary adj electron and resolution with beam and "250"/\$.ccls.	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 15:54
S37	98	scanning adj electron adj microscope and auger adj electron and efficiency	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 16:38
S38	9	scanning adj electron adj microscope and auger adj electron and collection adj efficiency	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/22 16:39
S39	16	"250"/\$.ccls. and electron adj beam and lens and shield and conductive and resistive	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/23 08:18
S40	151	"250"/\$.ccls. and electron adj beam and objective adj lens and shield	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/23 08:49
S41	102	"250"/\$.ccls. and electron adj beam and objective adj lens and electrostatic adj deflector	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/23 08:26
S42	23	"250"/\$.ccls. and electron adj beam and objective adj lens and electrostatic adj deflector not magnetic	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/23 08:27
S43	10	("250"/\$.ccls. and electron adj beam and objective adj lens and electrostatic adj deflector not magnetic) and secondary adj electron	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/23 08:27

S44	20	"250"/\$.ccls. and electron adj beam and objective adj lens and deflector and auger adj electron	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/23 10:48
S45	6	"250"/\$.ccls. and electron adj beam and lens and deflector and auger adj electron and capacitor	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/23 10:41
S46	19	"250"/\$.ccls. and electron adj beam and objective adj lens and deflector and auger adj electron and image	USPAT; EPO; JPO; DERWENT	OR	ON	2003/04/23 10:48
S47	507	"250"/\$.ccls. and ((scanning electron microscope) SEM) and auger	USPAT; EPO; JPO; DERWENT	OR	ON	2004/08/05 07:59
S48	224	("250"/\$.ccls. and ((scanning electron microscope) SEM) and auger) and deflect\$5	USPAT; EPO; JPO; DERWENT	OR	ON	2004/08/05 07:45
S49	76	((250"/\$.ccls. and ((scanning electron microscope) SEM) and auger) and deflect\$5) and objective adj lens	USPAT; EPO; JPO; DERWENT	OR	ON	2004/08/05 07:45
S50	92	("250"/\$.ccls. and ((scanning electron microscope) SEM) and auger) and objective adj lens	USPAT; EPO; JPO; DERWENT	OR	ON	2004/08/05 08:00